

<b>Notice of References Cited</b>	Application/Control No. 10/807,425		Applicant(s)/Patent Under Reexamination SASAKI ET AL.	
	Examiner Paul D. Kim		Art Unit 3729	Page 1 of 1

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*	B	US-6,301,079	10-2001	Hanamoto et al.	360/236.5
*	C	US-5,841,608	11-1998	Kasamatsu et al.	360/236.6
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.